**Title of the article**

Anna Auhtora, Bartłomiej Auhtor

a Silesian University of Technology, Faculty of Mechanical Engineering, Department of Engineering Materials and Biomaterials

email: xxxx@polsl.pl

**Abstract:** Describe briefly what the article is about and what has been done.

For example: The article describes the idea of the atomic layer deposition method and its possible applications. Also presented are the exemplary test results of Al2O3 thin layers deposited by the ALD method on the Picosun R-200 system.

**Keywords**: materials, laser treatment, polimers

**1. INTRODUCTION**

All text is written on the **maximum 4 pages** in Times New Roman size 12 font, main points are written in CAPITAL LETTERS in bold, and sub-points are written "normal" also in bold.

The first line of the paragraph is indented 0.5 cm and the line spacing is 1 line (single), the text is justified.

**1.1. Sub-point**

References to the literature are placed in square brackets []. Bullets are dots (indent the first line and other lines (protrusion) 0.5 cm from the dot, protrusion of the dot 0) as in the example below:

• XXX

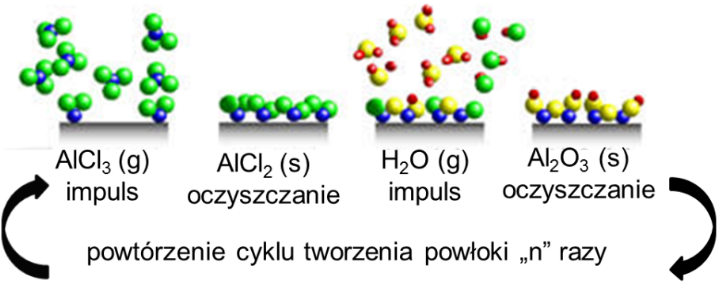
using subnumbering as in the example below:

▪ XXX

Numbering (first line indentation and other lines (protrusion) 0.5 cm, digit 0 protrusion) as in the example below:

1. xxxx

Descriptions of drawings justified: in Polish (simple text) and in English (italics), as shown in the example below:



*Figure 1. Deposition of Al2O3 monolayer by ALD method*

Descriptions of tables justified: in Polish (simple text) and in English (italics), as shown in the example below. Board border ½ point, width 16 cm.

*Table 1. Technical specifications High temperature vacuum furnace HT-2100-G-Vac-Graphit-Special the company LINN*

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